

Claim Amendments

This listing of the claims will replace all prior versions, and listings, of claims in the application:

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Claim 1 (currently-amended): An installation for fabricating semiconductor products, comprising:

C<sub>1</sub> fabrication units performing etching processes, wet chemical processes, diffusion processes, and cleaning techniques and being configured to operate in a clean room having longitudinal inner walls;

a transport system including a portal crane installation for supplying the semiconductor products to said fabrication units, said portal crane installation being configured to extend across the entire clean room and including two parallel crane tracks disposed in an opposing fashion in vicinity of said longitudinal inner walls, a holding device extendable in a vertical direction, a carrier including a rail guide, said carrier having longitudinal sides, said two parallel crane tracks extending above said fabrication units, said carrier extending transverse to said two parallel crane tracks, and said carrier having ends at said longitudinal sides movably mounted in said two parallel crane tracks;

said portal crane installation including a bogie guided in  
said rail guide;

said fabrication units being disposed in the clean room at  
positions independent of said transport system;

said fabrication units and said transport system configured to  
process semiconductor wafers; and

C<sub>1</sub>  
a transport container fixed to said bogie via said holding  
device and movably mounted to said holding device such that  
said transport container is guidable over said fabrication  
units and is lowerable to said fabrication units.

Claim 2 (previously-presented): The installation according to  
claim 1, wherein said carrier includes bogies respectively  
disposed at said ends of said carrier.

Claim 3 (original): The installation according to claim 2,  
wherein each of said two parallel crane tracks includes a rail  
guide for a respective one of said bogies.

Claim 4 (original): The installation according to claim 1, including support pillars, said two parallel crane tracks being supported on said support pillars.

Claim 5 (original): The installation according to claim 1, wherein said transport container is movable along said carrier.

C, ~~Claims 6 and 7 (cancelled)~~

Claim 8 (previously-presented): The installation according to claim 1, wherein said portal crane installation includes a swivel mechanism disposed between said holding device and said transport container, said swivel mechanism moves said transport container horizontally relative to said holding device for fine positioning said transport container.

Claim 9 (original): The installation according to claim 1, including a numerical control system controlling a travel path of said transport container along said carrier.

Claim 10 (original): The installation according to claim 1, wherein said portal crane installation includes drives with respective encapsulations.

Claim 11 (original): The installation according to claim 10, wherein said encapsulations are explosion-proof encapsulations.

Claim 12 (original): The installation according to claim 2, wherein said bogies have respective encapsulations.

Claim 13 (previously-presented): The installation according to claim 1, wherein said bogie has an encapsulation.

C<sub>1</sub> Claim 14 (original): The installation according to claim 2, wherein said two parallel crane tracks have contact surfaces in contact with said bogies, said contact surfaces and said bogies are formed of a wear-proof, non-outgassing material.

Claim 15 (previously-presented): The installation according to claim 1, wherein said rail guide of said carrier has a contact surface in contact with said bogie, said contact surface and said bogie are formed of a wear-proof, non-outgassing material.

Claim 16 (original): The installation according to claim 1, including a central control system controlling said portal crane installation.

Claims 17-19 (cancelled)

Claim 20 (original): The installation according to claim 1, wherein said portal crane installation includes a further carrier and a further transport container movably mounted to said further carrier, said further carrier moves on said two parallel crane tracks of said portal crane installation.

C Claim 21 (original): The installation according to claim 20, wherein said carrier and said further carrier are individually movable in said portal crane installation.

Claim 22 (original): The installation according to claim 1, wherein said portal crane installation includes a further transport container, said transport container and said further transport container are movably mounted one behind another to said carrier.

Claim 23 (original): The installation according to claim 22, wherein said transport container and said further transport container are individually movable.

Claim 24 (cancelled)

Claim 25 (currently-amended): A plant for fabricating  
semiconductor products, comprising:

a clean room having longitudinal inner walls;

fabrication units performing etching processes, wet chemical  
processes, diffusion processes, and cleaning techniques and  
being disposed in said clean room;

C,  
a transport system including a portal crane installation for  
supplying the semiconductor products to said fabrication  
units, said portal crane installation being configured to  
extend across said entire clean room and including two  
parallel crane tracks disposed in an opposing fashion in  
vicinity of said longitudinal inner walls, a holding device  
extendable in a vertical direction, a carrier including a rail  
guide, said carrier having longitudinal sides, said two  
parallel crane tracks extending above said fabrication units,  
said carrier extending transverse to said two parallel crane  
tracks, and said carrier having ends at said longitudinal  
sides movably mounted in said two parallel crane tracks;

said portal crane installation including a bogie guided in  
said rail guide;

Applic. No. 10/014,246  
Amdt. dated January 26, 2004  
Reply to Office action of September 24, 2003

said fabrication units being disposed in said clean room at  
positions independent of said transport system;

said fabrication units and said transport system being  
configured to process semiconductor wafers; and

C<sub>1</sub> a transport container fixed to said bogie via said holding  
device and movably mounted to said holding device such that  
said transport container is guidable over said fabrication  
units and is lowerable to said fabrication units.

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